

Form PTO 1449 (Rev. 2-32)	U.S. Department of Commerce Patent and Trademark Office	Atty. Docket No. LMPY-10910	Serial No.: 09/733,874
Information Disclosure Statement by Applicant		Applicant: Michael J. Scaggs	
(Use several sheets if necessary)		Filed: December 8, 2000 Group: 2881	

## U.S. Patent Documents

Init.	Document No.	Date	Name	Class	Subclass	Filing Date
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2	5,221,823	06/22/93	Usui	219	121.78	01/17/92
2	5,440,587	08/08/95	Ishikawa et al.	375	332	07/08/94
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## Foreign Documents

Translation							
Init.	Document No.	Date	Country	Class	Subclass	Yes	No
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3	EP 0 790 681 A2	08/20/97	EPO	H01S	3/134	X	
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3	WO 98/59364	12/30/98	PCT	H01L	21/027		X
3	WO 99/04467	01/28/99	PCT	H01S	3/134	X	
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Examiner	Date Considered <i>12/10/02</i>
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<div style="position: absolute; left: -100px; top: -100px; border: 1px solid black; border-radius: 50%; padding: 5px; text-align: center;">             O I P E              DEC 18 2001              PATENT &amp; TRADEMARK OFFICE           </div> Information Disclosure Statement by Applicant		Applicant: Michael J. Scaggs	
(Use several sheets if necessary)		Filed: December 8, 2000 Group: 2881	
<b>Other Documents (Including Author, Title, Date, Pertinent Pages, etc.)</b>			
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